| Ref # | Hits | Search Query | DBs | Default Operator | Plurals | Time Stamp |
|----------|--------|--|---|---------------------|---------|------------------|
| [5] | 2983 | (hydrophilic) and wafer and bonding | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:37 |
| L2 | 4264 | (hydrophilic or hydrophobic) and wafer and bonding | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:37 |
| L3 | 650 | (hydrophilic or hydrophobic).clm. and wafer and bonding | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:37 |
| L4 | 594113 | (hydrophilic or hydrophobic).clm. and wafer ".clm.and" bonding | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:38 |
| L5 | 48 | (hydrophilic or hydrophobic).clm. and wafer.clm. and bonding.clm. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:38 |
| L6 | 31 | (hydrophilic or hydrophobic).clm. and wafer.clm. and bonding.clm. and semiconductor | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:38 |
| L7 | 21 | (hydrophilic or hydrophobic).clm. and wafer.clm. and bonding.clm. and semiconductor.clm. and layer. clm. | US:PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:39 |
| L8 | 9 | (hydrophilic or hydrophobic).clm. and wafer.clm. and bonding.clm. and semiconductor.clm. and layer. clm. and (crystal or crystalline or crystallographic).clm. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:40 |
| L9 | 5 | (hydrophilic or hydrophobic).clm. and wafer.clm. and bonding.clm. and semiconductor.clm. and layer. clm. and (crystal or crystalline or crystallographic).clm. and orientation.clm. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:40 |

| L10 | 0 | interface.clm. and (hydrophilic or hydrophobic).clm. and wafer.clm. and bonding.clm. and semiconductor.clm. with layer.clm. with (crystal or crystalline or crystallographic).clm. with orientation.clm. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:41 |
|-----|-----|--|---|----|----|------------------|
| 111 | 0 | (hydrophilic or hydrophobic).clm. with semiconductor.clm. with layer.clm. with (crystal or crystalline or crystallographic).clm. with orientation.clm. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:41 |
| L12 | | (hydrophilic or hydrophobic) with semiconductor with layer with (crystal or crystalline or crystallographic) with orientation | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:41 |
| L13 | 2 | (semiconductor adj layer) with (interface) with (hydrophobic or hydrophilic) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:43 |
| L14 | 578 | (layer) with (interface) with (hydrophobic or hydrophilic) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:44 |
| L15 | 52 | ((layer) with (interface) with (hydrophobic or hydrophilic)).clm. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:44 |
| L16 | 5 | ((layer) with (interface) with (hydrophobic or hydrophilic)).clm. and (crystal or crystalline or crystallographic).clm. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:45 |
| L17 | 1 | ((layer) with (interface) with (hydrophobic or hydrophilic)).clm. and (crystal or crystalline or crystallographic).clm. and (direct near5 bonding) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:47 |
| L18 | 0 | ((layer) near10 (interface) near10 (hydrophobic or hydrophilic)).clm. and (crystal or crystalline or crystallographic).clm. and (direct near5 bonding) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:47 |
| L19 | 4 | ((layer) near10 (interface) near10 (hydrophobic or hydrophilic)).clm. and (crystal or crystalline or crystallographic).clm. | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:48 |

| L20 | 3 | ((layer) near10 (interface) near10 (hydrophobic or hydrophilic)).clm. and (crystal or crystalline or crystallographic).clm. and wafer | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 08:48 |
|-----|---|---|---|----|----|------------------|
| L21 | 3 | ((layer) near10 (interface) near10 (hydrophobic or hydrophilic)).clm. and (crystal or crystalline or crystallographic).clm. and (wafer near2 bonding) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 10:33 |
| L22 | 4 | ((layer) near10 (interface) near10 (hydrophobic or hydrophilic)) and (crystal or crystalline or crystallographic).clm. and (wafer near2 bonding) | US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB | OR | ON | 2005/02/21 10:34 |